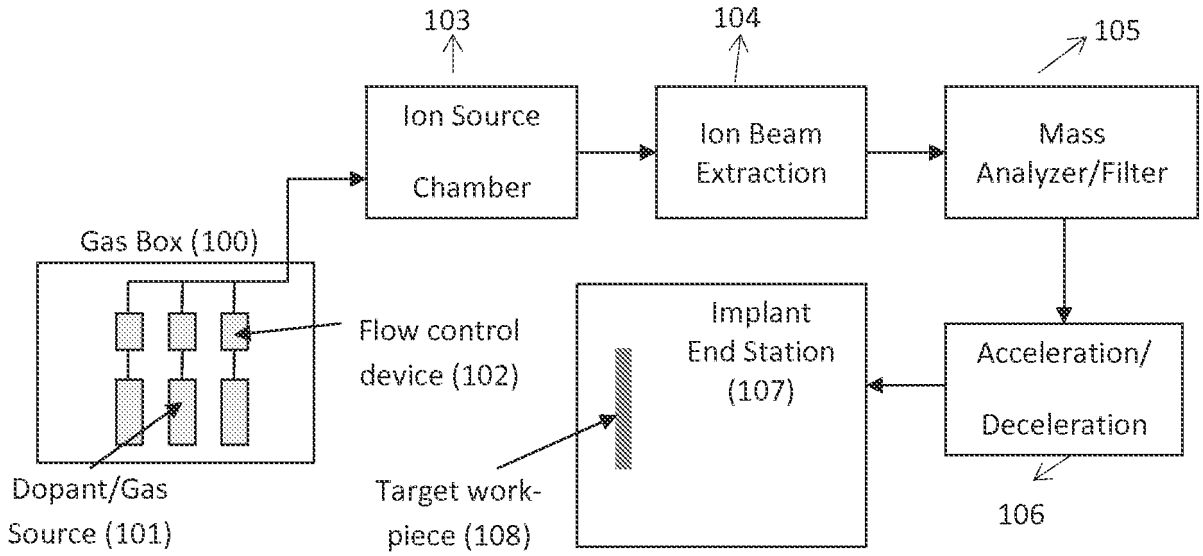
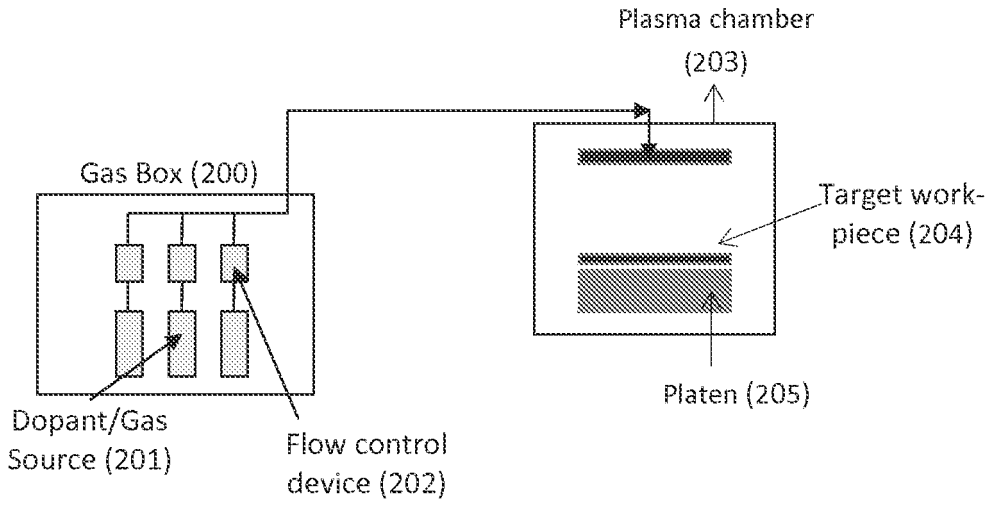


Schematic of beamline ion implant system

FIG. 1



Schematic of plasma immersion ion implant system

FIG. 2

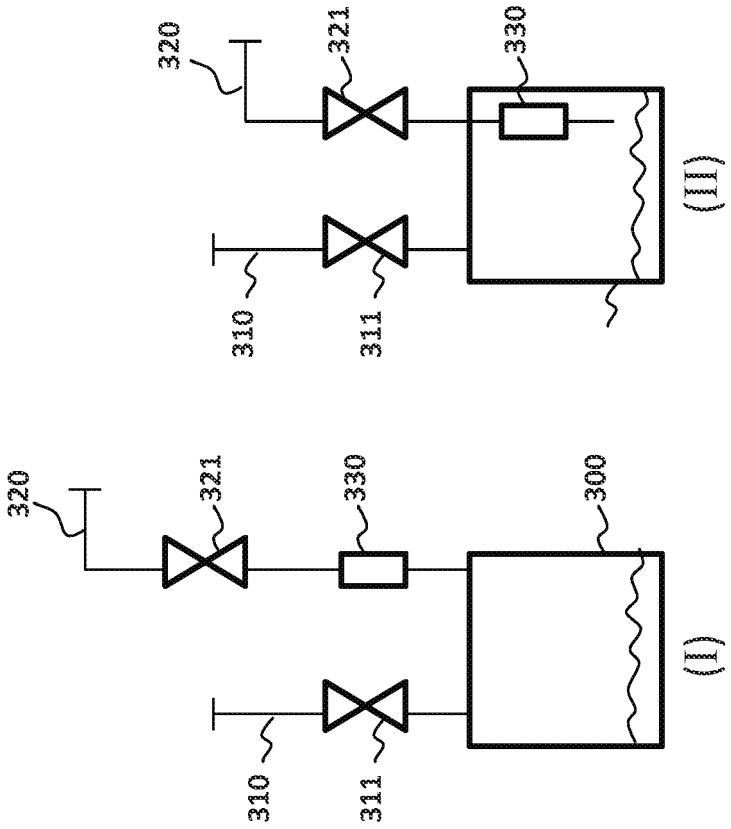

320
321
330
300
310
311
(I)
320
321
330
310
311
(II)
Package for Al dopant materials

FIG. 3